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APPLICANTS	APPLICATION NO. 09/609347	CONT/PRIOR D	CLASS 204	SUBCLASS 212	ART UNIT 1741	EXAMINER Smith, Hicks Mutschler
	Robin Cheung Ashok Sinha Avi Tepman Dan Carl					
TITLE	Apparatus for electro chemical deposition of copper metallization with the capability of in-situ thermal annealing					

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[illegible]

<b>TERMINAL DISCLAIMER</b> <input type="checkbox"/> The term of this patent subsequent to _____ (date) has been disclaimed. <input checked="" type="checkbox"/> The term of this patent shall not extend beyond the expiration date of U.S. Patent No. <u>6,136,163</u> _____ _____	<b>DRAWINGS</b> Sheets Drawn: _____ Figs. Drawn: _____ Print Fig: _____			<b>CLAIMS ALLOWED</b> Total Claims: _____ Print Claim for O.G.: _____	
	_____ (Assistant Examiner) _____ (Date)			<b>NOTICE OF ALLOWANCE MAILED</b> _____ _____	
<input type="checkbox"/> The terminal _____ months of this patent have been disclaimed. _____ _____	_____ (Primary Examiner) _____ (Date)			<b>ISSUE FEE</b> Amount Due: _____ Date Paid: _____	
	_____ (Legal Instruments Examiner) _____ (Date)			<b>ISSUE BATCH NUMBER</b> _____	

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